



# Certificate of Presentation

We hereby certify that the work  
**Evolution of pseudo-MOS measurements in JL-FET structures according to  
silicon etching time in NH<sub>4</sub>OH solution**

by

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was presented at the XIV Workshop on Semiconductors and Micro & Nano  
Technology, in Campinas-SP, held on April 11-12, 2019.

A handwritten signature in blue ink, reading "Jacobus Swart", written over a horizontal line.

Dr. Jacobus Swart  
SEMINATEC 2019 General Chair